



PATENT

Atty. Dkt. No. AMAT/4969/CMP/ECP/RKK

100

~~~~~

Group Art Unit: 1763

Serial No.: 09/785,815

Examiner: Sylvia MacArthur

Confirmation No.: 4127

Filed: February 16, 2001

For: Integrated Semiconductor  
Substrate Bevel Cleaning  
Apparatus and Method

RECEIVED

JUL 09 2003

OFFICE OF PETITIONS

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

CERTIFICATE OF MAILING  
37 CFR 1.8

I hereby certify that this correspondence is being deposited on June 25, 2003 with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

6/25/03  
Date

B. Todd Patterson  
Signature

## STATEMENT OF COMMON OWNERSHIP

The present application (Serial No. 09/785,815; hereinafter the “Application”) and Patent No. 6,516,815 (*Stevens, et al.*) were, at the time the invention of the Application was made, owned by, or subject to an obligation of assignment to, Applied Materials, Inc.

Respectfully submitted,

B. Todd Patterson

**B. Todd Patterson**  
Registration No. 37,906  
**MOSER, PATTERSON & SHERIDAN, L.L.P.**  
3040 Post Oak Blvd., Suite 1500  
Houston, Texas 77056  
(713) 623-4844  
**ATTORNEY FOR APPLICANT**

BEST AVAILABLE COPY